Special Issue

Recent Advances in Metal Oxide Thin Films and Nanostructures for Diverse Applications

Message from the Guest Editor

We would like to invite you to submit your work to this Special Issue, focused on “Recent Advances in Metal Oxide Thin Films and Nanostructures for Diverse Applications”. This Special Issue aims to provide a snapshot of the state of the art in the preparations, characterizations, and applications of MO thin films and nanostructures. In particular, the topics of interest include, but are not limited to, the following:

- MO thin film growths and characterization techniques;
- Synthesis of MO nanostructures, properties, and applications;
- Nanomechanical properties of MO thin films and nanostructures studied by the nanoindentation technique;
- Photocatalytic degradation of pollutants and photoelectrochemical activity of MO thin films and nanostructures;
- Functional properties and applications of MO thin films and nanostructures (e.g., HER, fuel cells, solar cells, hard coatings, antimicrobial activity, anti-bacteria, photodetectors, sensing, electronic devices, optoelectronics, memories, etc.);
- Theory, modeling, atomistic simulation, and numerical analysis of MO thin films and nanostructures.

Guest Editor

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Deadline for manuscript submissions

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Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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